OPE					Docket Number (Optional)		Application Number 10/666,330											
INFORMATION DISCLOSURE CITATION					P 6121.62022 Applicant(s)													
JAN 1		<b>T</b>	ary)	Artur G. Olszak and Michael R. Descour														
A					Filing Date September 19,		Group Art Unit											
September 19, 2003  U.S. PATENT DOCUMENTS																		
*EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE		NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE										
74		5,260,826	11/9/93	Wu														
4	٠	6,133,986	10/17/00	Johnson														
PF		6,320,174 B1	11/20/01	Tafas et al.														
74		6,373,978 B1	4/16/02	Ishihara			>											
PP		6,512,573 B2	1/28/03	Furter														
						<u> </u>												
				<u> </u>			<u> </u>											
•					•													
· 💰					•													
				٠,	•													
,	,																	
FOREIGN PATENT DOCUMENTS																		
	REF	DOCUMENT NUMBER DATE		COUNTRY		CLASS SUBCLASS		Translation YES NO										
P	•	GB 2,351,556 A	4/20/00 Unite		Kingdom	G01N	21/64											
							<u></u>											
				<u> </u>														
						Author, Title, D												
(3)	9	Hans J. Tiziani and Ha Optics, 1 February 199	ns-Martin Uhde, 4, Vol. 33, No. 4,	"Three-dir pps. 567-57	nensional analysis by a m 72	ncrolens-array	contocal arran	igement," Applied										
1	4		•	•														
-																		
				•			·											
EXAMINER DATE CONSIDERED (2-28-04)																		
		al if citation considered, whether						in conformance and										
				-66-100000				not considered. Include copy of this form with next communication to applicant.										

					Docket Number (Optional) P 6121.62022	Application Number 10/666,330					
101	NFO	MATION DISCLOSUR	E CITATION		Applicant(s)						
		(L'se several sheets if necess	ary)	Artur G. Olszak and Michael Descour							
NOV 1	5 200	( 6			Filing Date		Group Art Unit	Group Art Unit . 2873 2851			
	- 100	<u>'                                    </u>			9/19/03 2873				-/-		
E.		EJ .		U.S. PAT	ENT DOCUMENTS				- 4		
EXAMENT INITIAL	REF	DOCUMENT NUMBER	DATE	NAME		CLASS	SUBCLASS	FILING DATE IF APPROPRIATE			
27		6,424,404	7/23/02	Johnson							
75		6,016,185	1/18/00	Cullman et al.							
					·						
								F-717			
				·							
				ļ	<del></del>						
					÷	ļ	<u> </u>				
				FOREIG	N PATENT DOCUMENTS		· · · · · · · · · · · · · · · · · · ·		•		
	REF	DOCUMENT NUMBER	DATE		COUNTRY	CLASS	SUBCLASS	Trens YES	NO NO		
3x		WO 97/34171	9/18/97	PCT		G02B					
								-			
					<u> </u>						
					•		Date, Pertinent Pa	_			
		R. Volkel, H.P. Herzig	, et al., "Microlei	ns Lithogra	phy and Smart Masks," M	licroelectric	Engineering 35	(1997), pps	. 513-516		
H	-										
PA	R. Volkel, H.P Herzig, et al., "Microlens array imaging system for photolithography," Opt. Eng. 35 (11), pps. 3323-3330 (November 1996)										
EVAMING		5///			DATE CONSIDERED						
EXAMINER						2-28-	c4				
EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP Section 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.											